



**Weapon Systems & Technology Directorate
US ARMY ARDEC and ARDEC- BENET Labs**

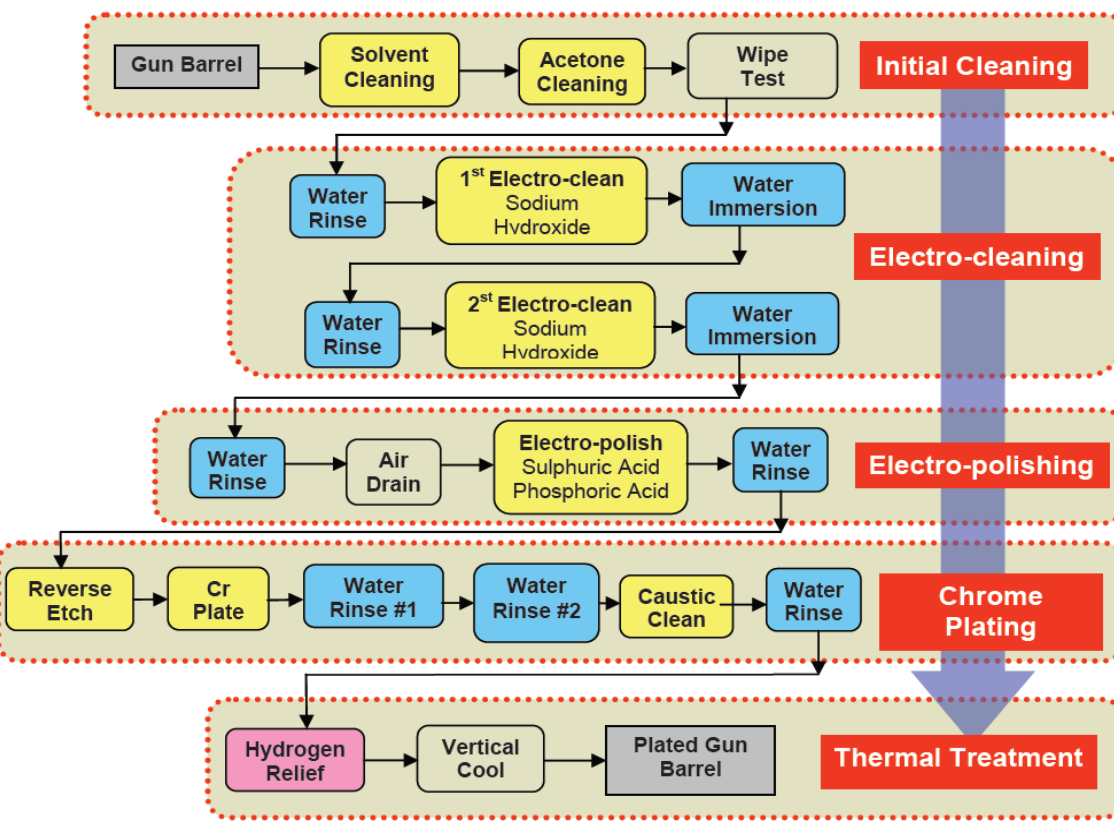
***New Physical Vapor Deposition Processes
for Durable Pollution-Free Ordnance***



TECHNOLOGY DRIVEN. WARFIGHTER FOCUSED.

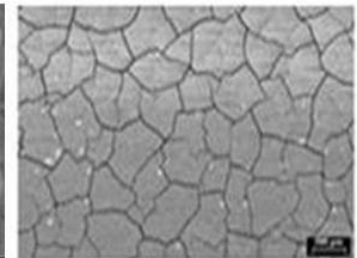
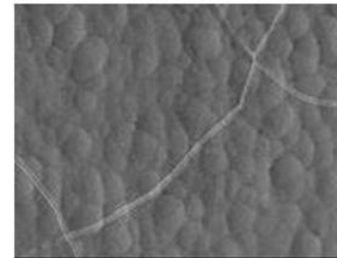
Dr. Sabrina Lee and Daniel Schmidt

***2011 NDIA Gun and Missile Conference
Miami, Florida, Aug 29- Sept 1, 2011***



As-deposited Cr

After-fired Cr

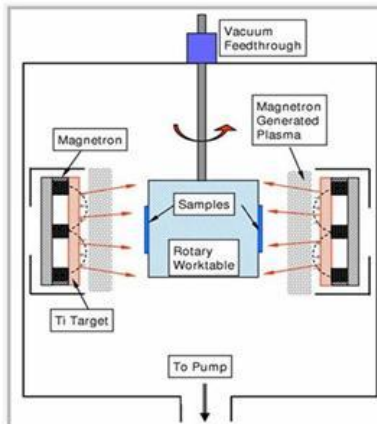


From- M. Audino. DOD Metal Plating Workshop, May 22, 2006.

- ❑ **Arc Evaporation (filtered, steered, switched) Process.**
- ❑ **Direct Current Magnetron Sputtering (DCMS) Process.**
- ❑ **Plasma Enhanced Magnetron Sputtering (PEMS).**
- ❑ **High Power Impulse Magnetron Sputtering (HIPIMS).**
- ❑ **PEMS/HIPIMS Deposited CrN Coatings and Applications.**
- ❑ **PEMS/HIPIMS Deposited Ta Coatings and Applications.**
- ❑ **Conclusions.**

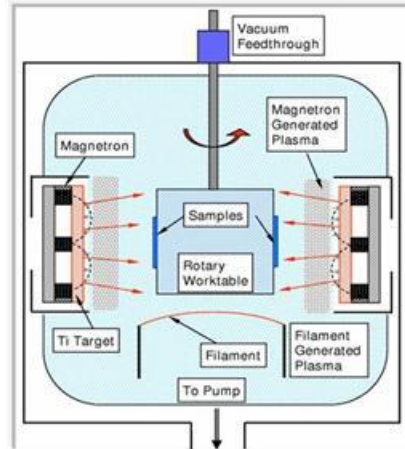
Multiple Target PVD- DCMS and PEMS systems at SWRI

DCMS (0.2mA/cm²)

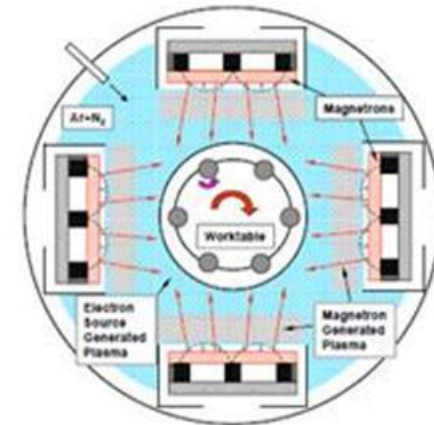


Aluminum

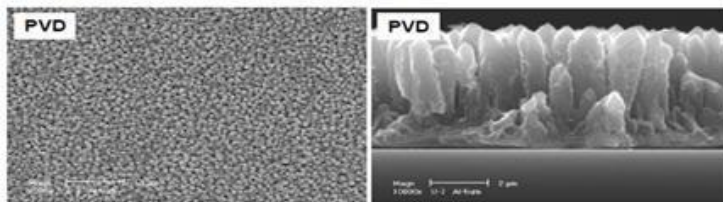
PEMS (4.9 mA/cm²)



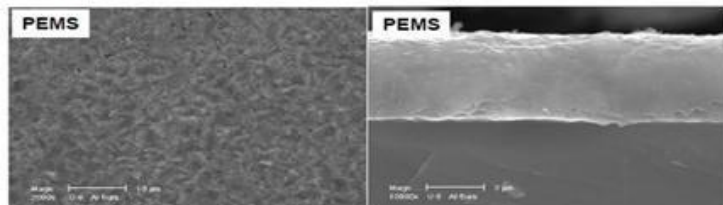
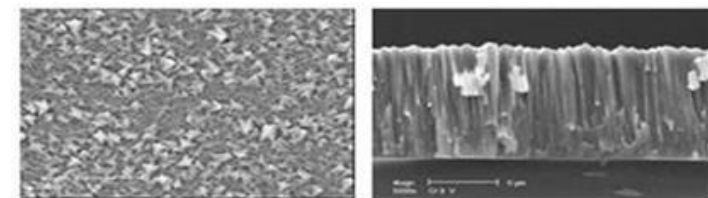
Multiple Target System



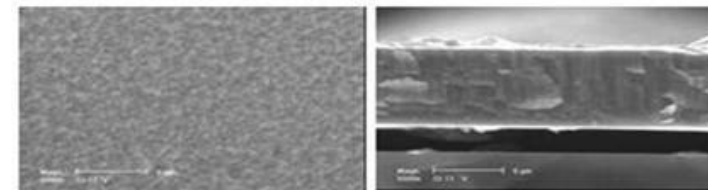
Chromium



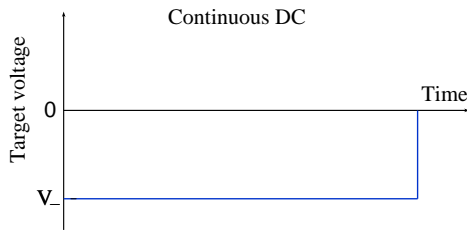
← DCMS →



← PEMS →

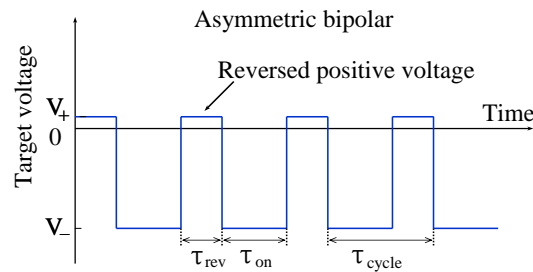


DCMS Continuous DC



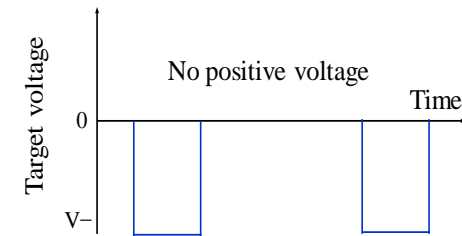
DCMS Pulsed DC

Frequency: in kHz
Duty cycle: 50~90%



HIPIMS-HPPMS-MPP*

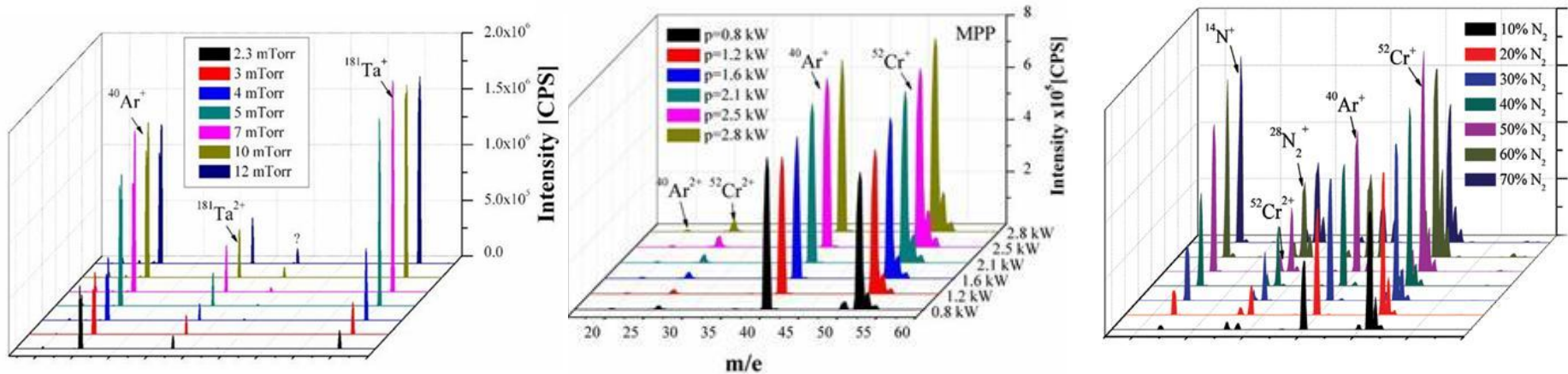
Frequency: in Hz
Duty cycle: 1-10%



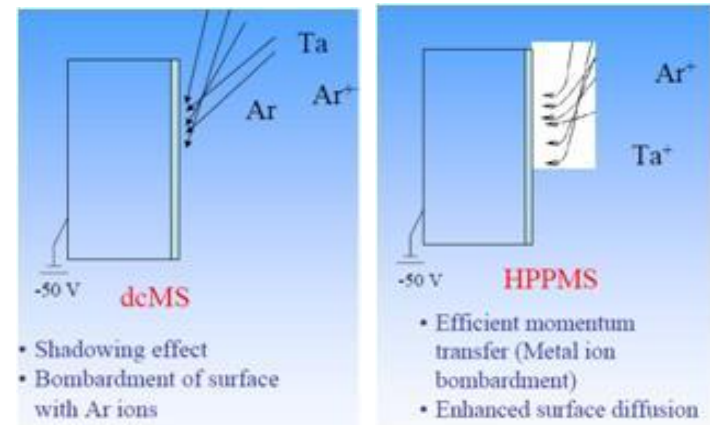
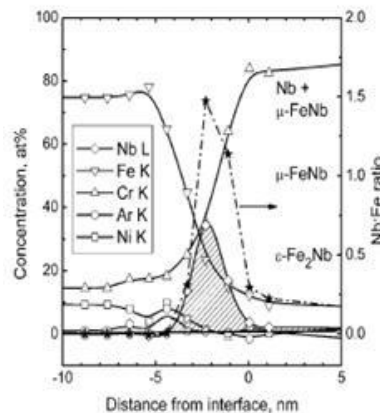
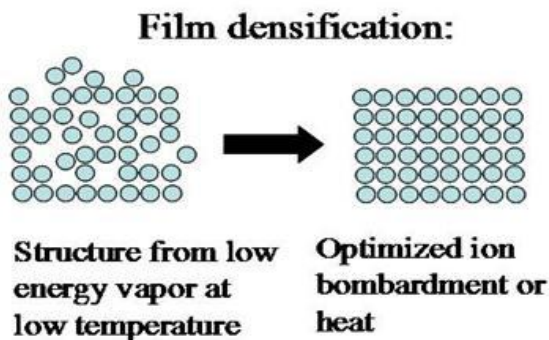
- **Introduced by Kouznetsov et al; HPPMS-MPP are slight variances of HIPIMS.*
- *Large number of target material ions and enhanced plasma density.*
- *High power pulses of short duration (100-150 μ s); low duty cycle (1-10%).*
- *Peak value (1-3 kW/cm²) typically 100 times greater than conventional DC magnetron sputtering (1-3 W/cm²).*

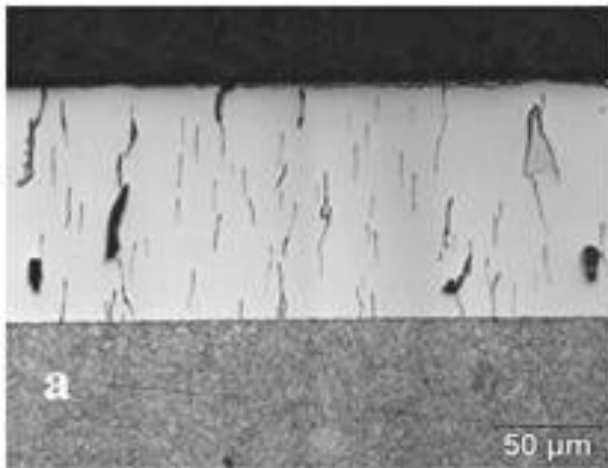
* From- V. Kouznetsov, K. Macák, J. M. Schneider, U. Helmersson, and I. Petrov, "A Novel Pulsed Magnetron Sputter Technique Utilizing Very High Target Power Densities," Surf. Coat. Technol. 122 (1999) 290.

- **High intensity target Metal Plasma Instead of Argon Plasma**
- **Deposition of dense coatings at low temperature on complex shape.**

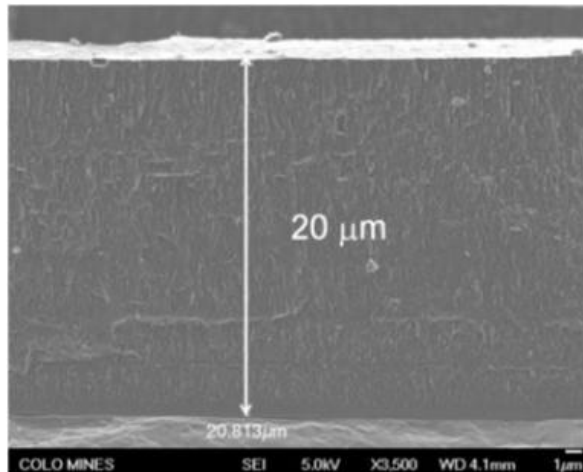


Plasma Mass-Ion Distribution using Tantalum and Chrome Targets measured using an electrostatic quadrupole plasma (EQP) mass spectrometer

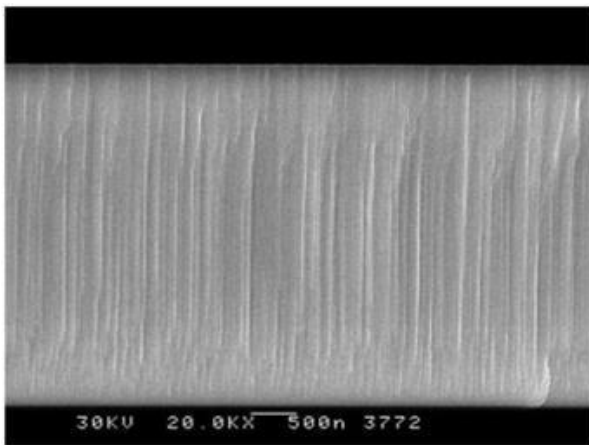
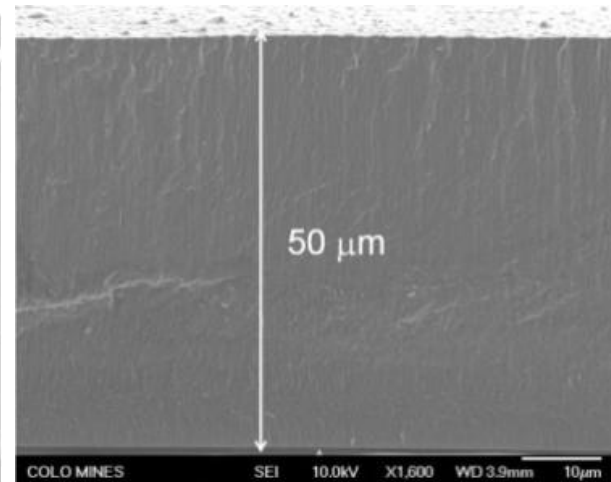




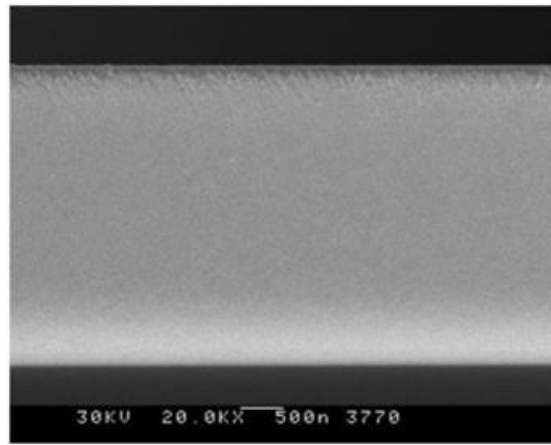
Production Electroplated Cr



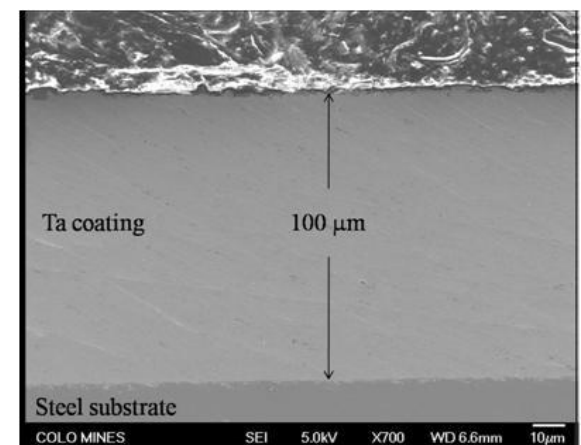
HIPIMS-MPP Deposited Thick CrN



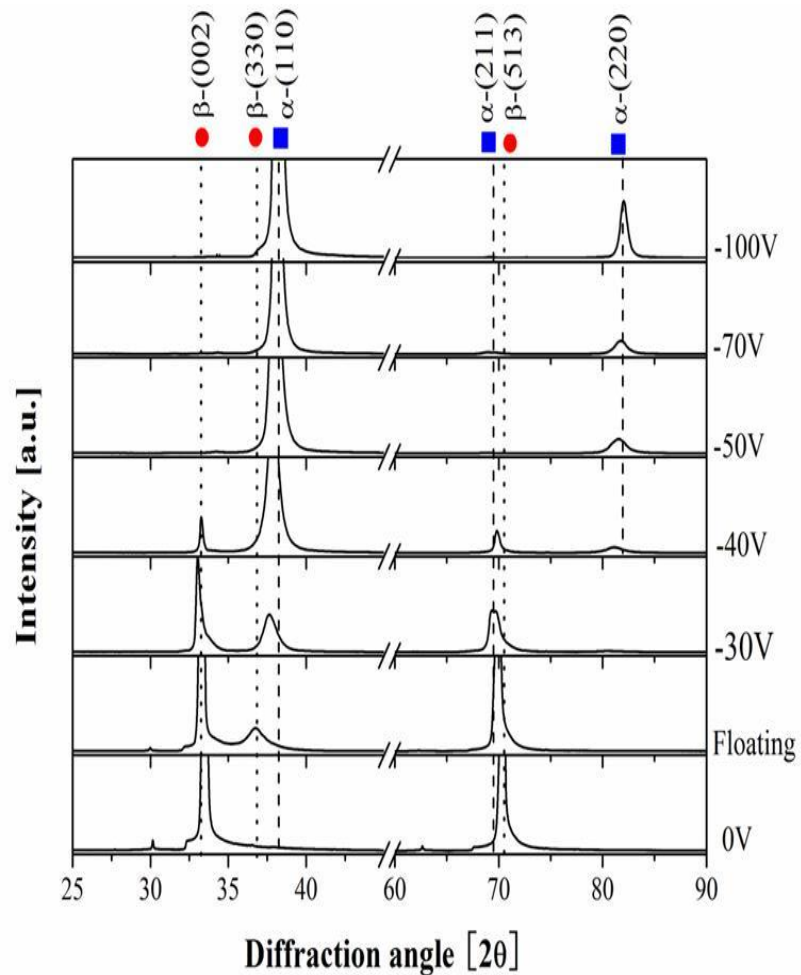
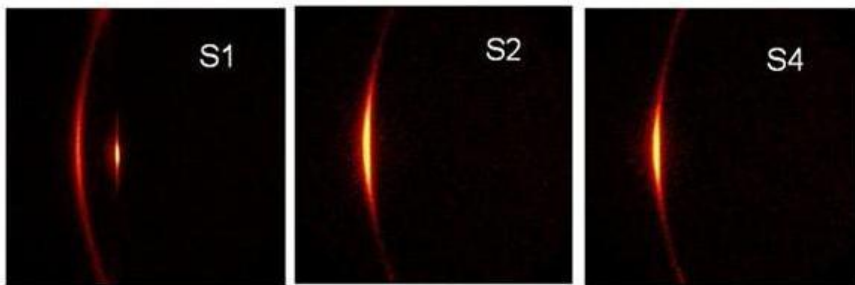
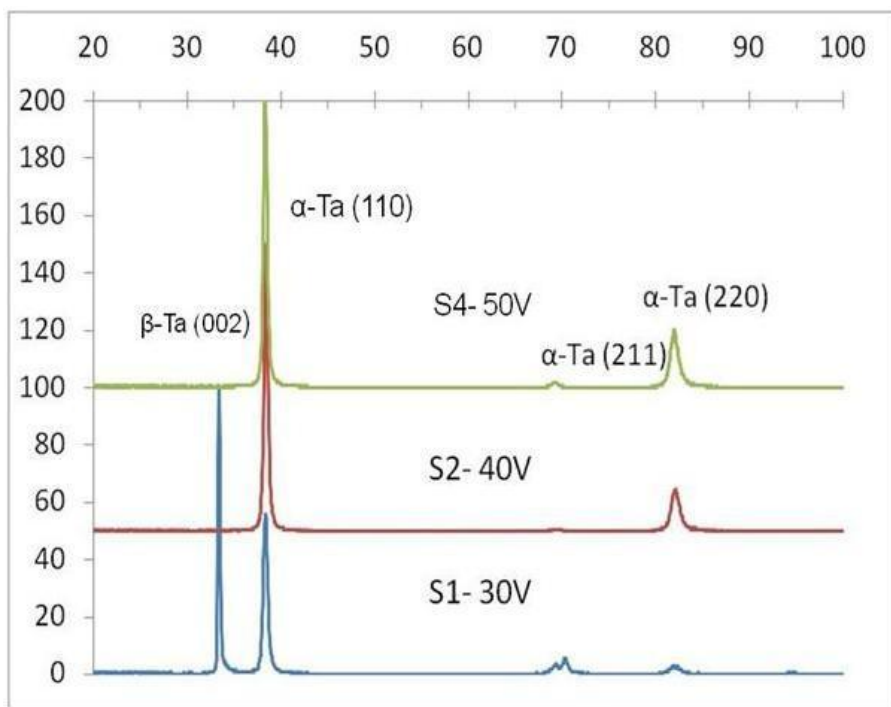
DCMS Ta (10μm)



HIPIMS Ta (10μm)



HIPIMS Ta (100μm)



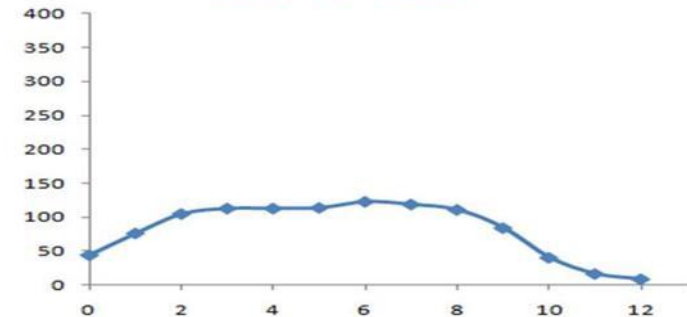
* From- S.L. Lee, M. Cipollo, F. Yee, R. Chistyakov, B. Abraham, SVC 52nd Tech Conf. Proc.,(2009) 44-49.

* From- J. Lin, J. Moore, W.D. Sproul, S.L. Lee, J. Wang, IEEE Transactions on Plasma Science, Vol 38, No. 11, (2010) 3071-3078.

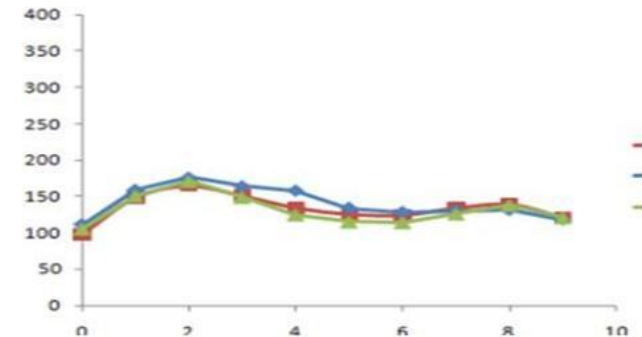


Adding biasing and HIPIMS-MPP to Benet DOE Cylindrical System

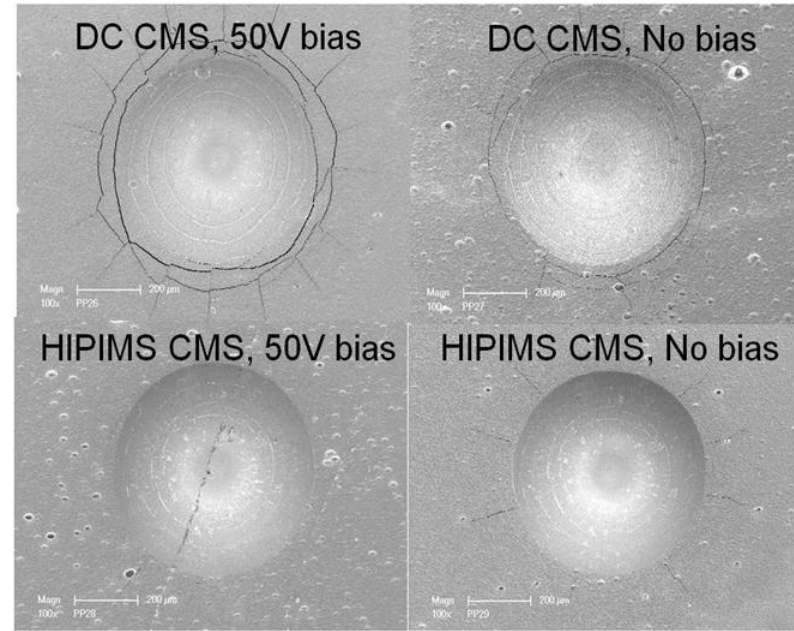
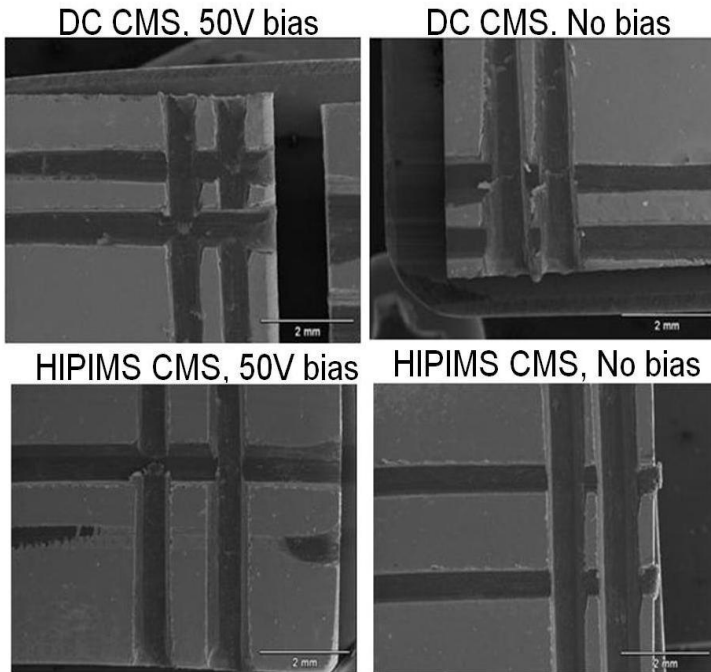
Benet DOE, HIPIMS-MPP Barrel
 8 hrs, 100-120 μ m thick
 blue- 6 o'clock



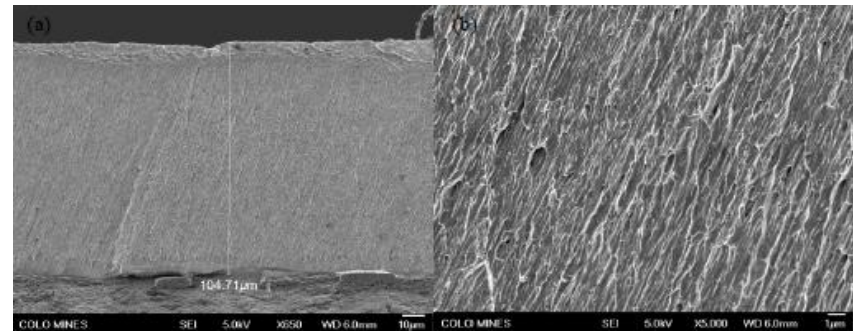
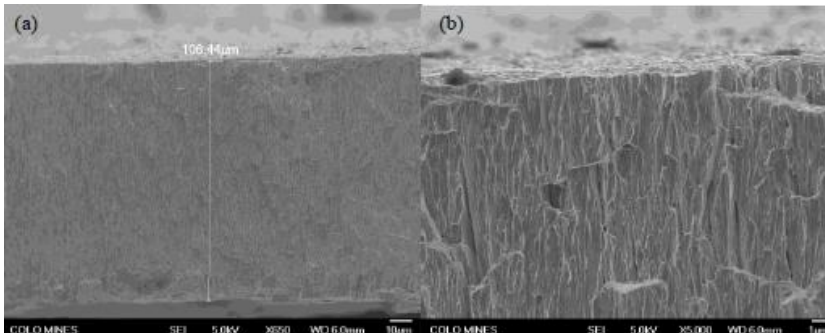
Tube PP36 on Carbon Tube; Biased DC, 15 hrs,
100-150 μ m thick; red- 6, blue- 9, green 12 o'clock



From- S.L. Lee, R. Wei, F. Yee, M. Cipollo, W. Sproul, J. Lin, presentation at ICMCTF, San Diego, CA, April 26-30, 2010.



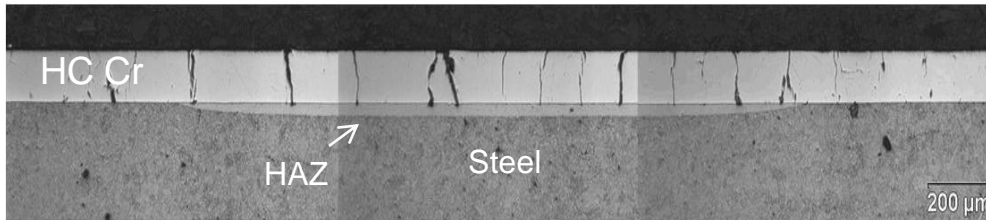
Fractured surface of 104-106 μm PEMS Ta on 1-ft long steel cylinder



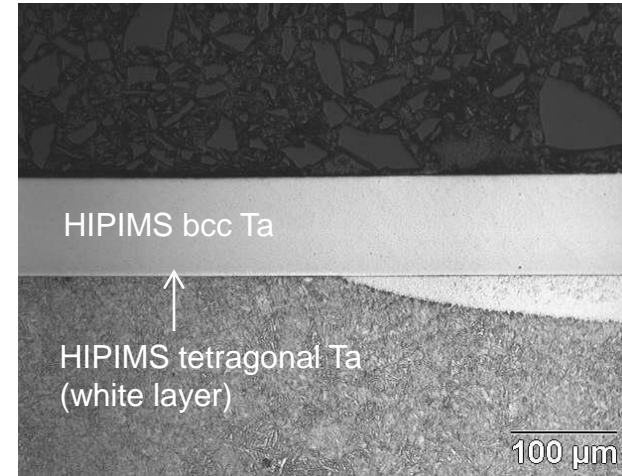
From- S.L. Lee, M. Todaro, S. Smith, R. Wei, K. Coulter, SVC 52nd Tech Conf. Proc., (2009) 558-563.

Pulse Laser Heating (2.5 msec, 1.0 J/mm², 20 cycles, simulating ~1400°C temperature)

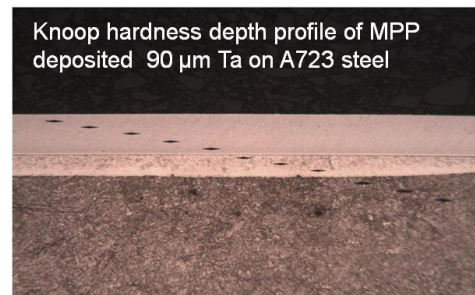
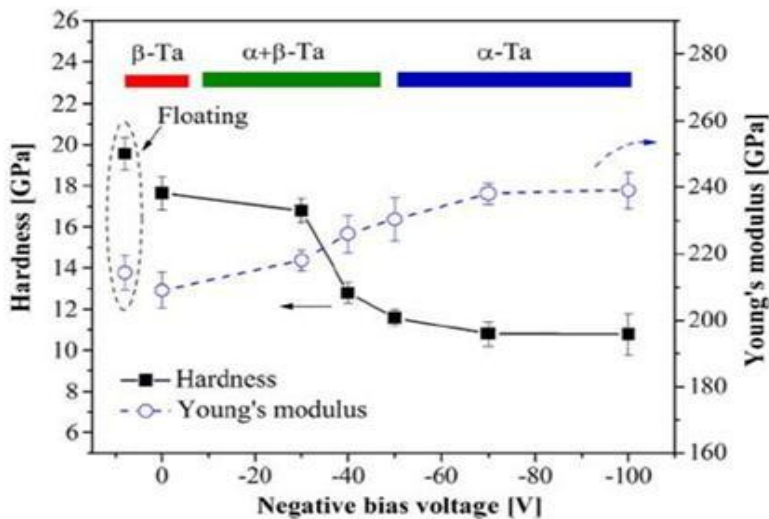
125 μm HC Cr on 120mm Diameter Steel Cylinder



90 μm HIPIMS-MPP Ta on Steel

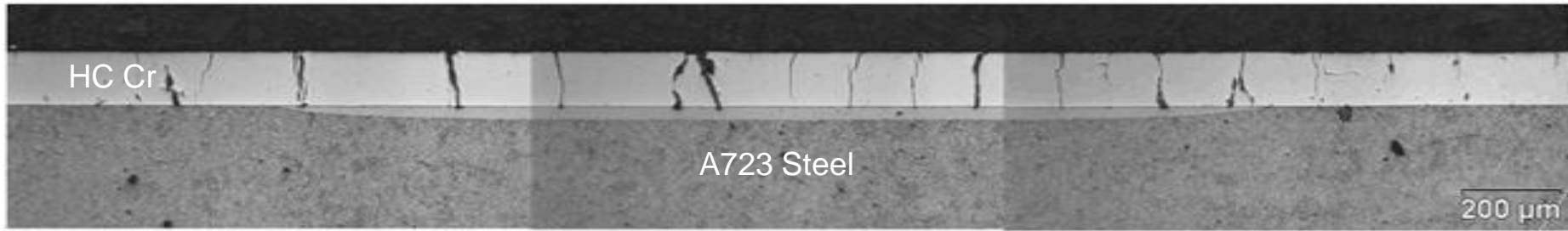


HAZ (Heat affected zone) in steel is due to tempered to untempered martensite transformation.



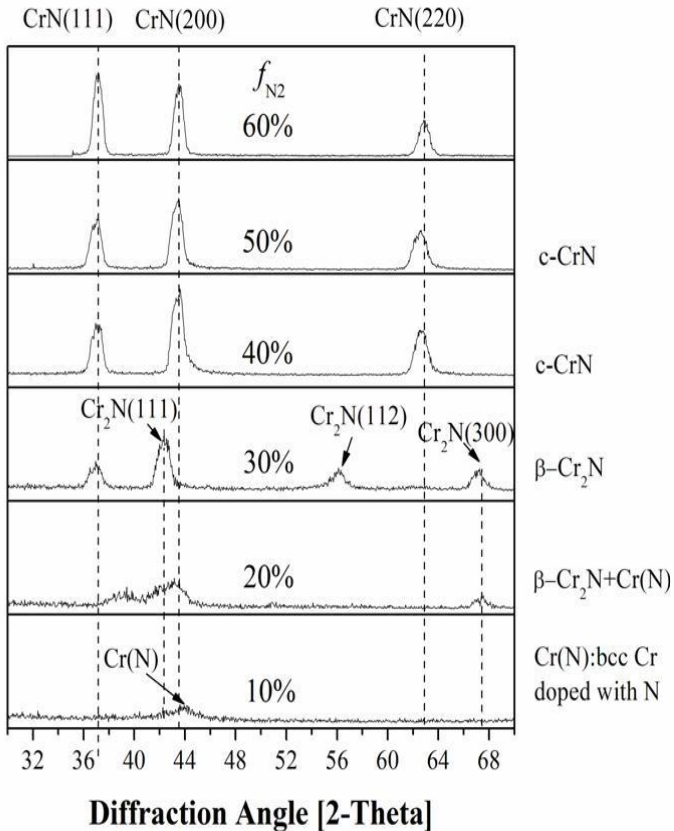
PL-Ta Mines 2-01			
Diamond Length (μ)	Knoop (Hk ₅₀)	Depth of Diamond (μ)	
36.64	530	-98.35	-Steel
37.57	505	-79.34	
39.68	451	-62.38	
29.54	815	-31.43	-HAZ
30.75	752	-16.72	
29.84	823	-6.63	
35.33	569	12.15	-Ta
34.52	598	28.53	
33.10	649	46.51	
33.10	649	61.02	
33.82	623	75.43	

- * Pulse Laser Heating (2.5 msec, 1.0 J/mm², 20 cycles, simulating ~1400°C temperature)
- * DOE-Z2-2 (MPP, substrate ground, 106 μm, no HAZ, no cracking, no delamination)

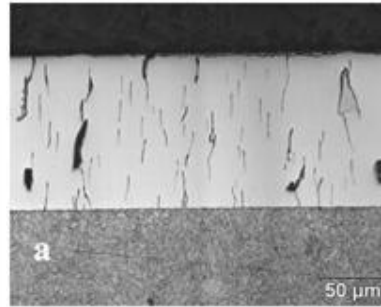


Z2-2		
Diamond Length (μ)	Knoop (Hk ₅₀)	Depth of Diamond (μ)
46.86	326	5.67
47.18	319	25.78
47.51	315	45.53
47.32	318	64.51
48.96	297	82.74

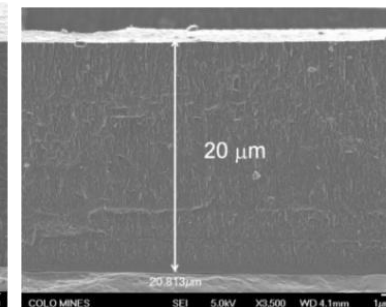
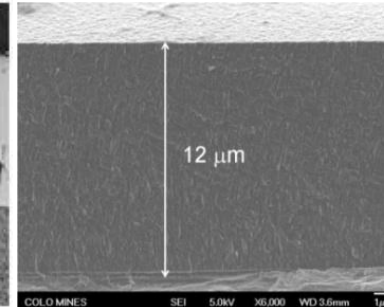
Phase formation of CrN coatings depends on the % N₂ in Ar gas.



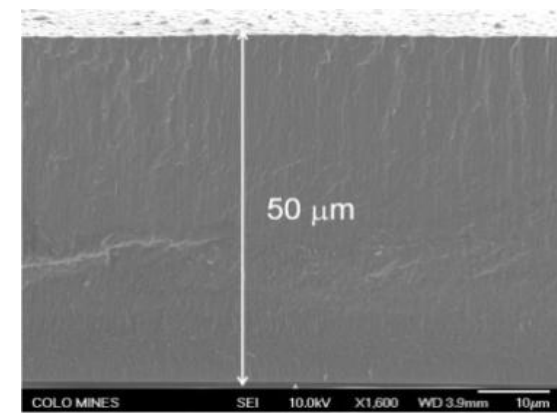
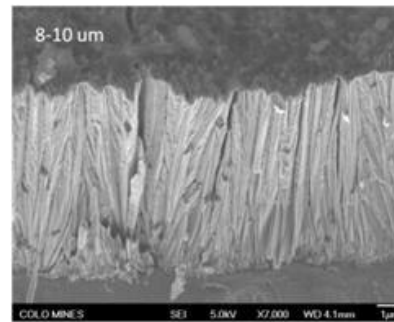
HC Cr



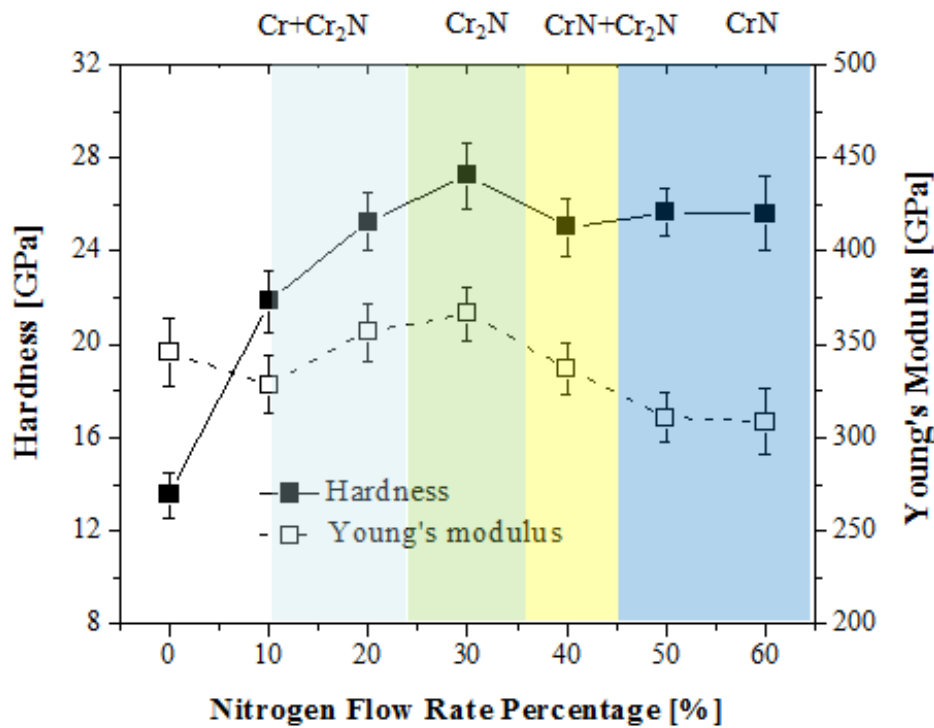
HIPIMS-MPP CrN



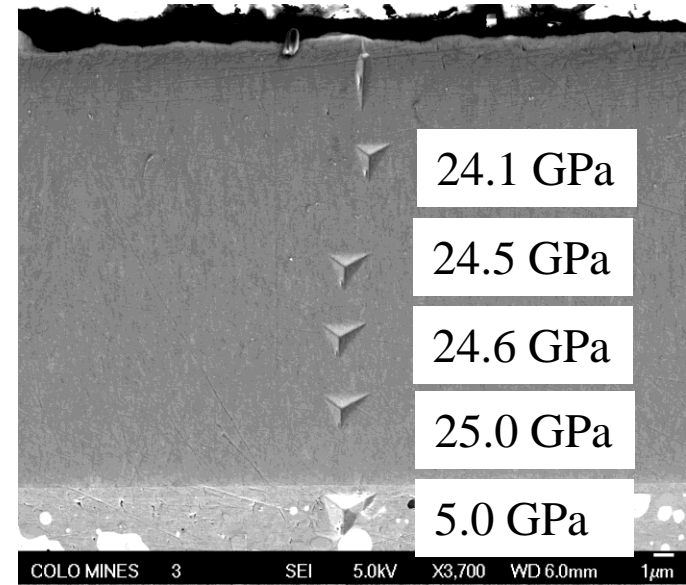
DCMS CrN



From- Jianliang Lin, William Sproul, John Moore, Sabrina Lee, S. Myers, *Surf Coat Tech* 205 (2010), 3226-3234.



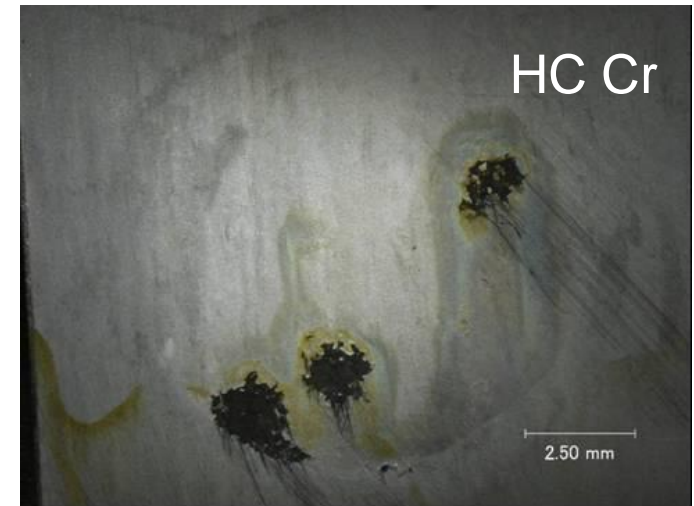
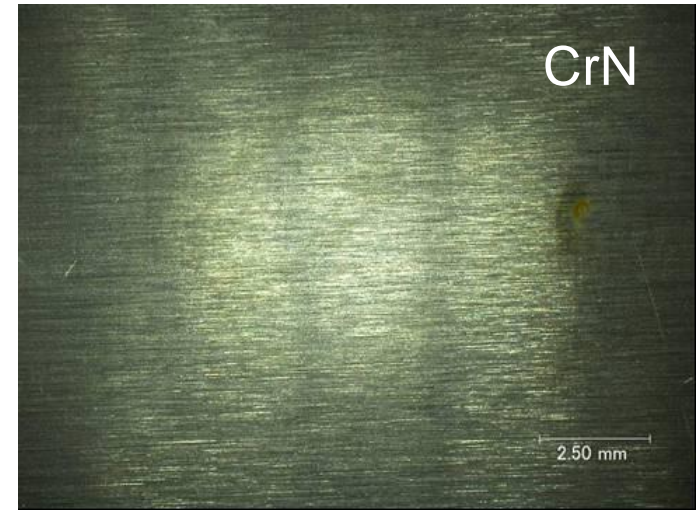
20 μm CrN coating



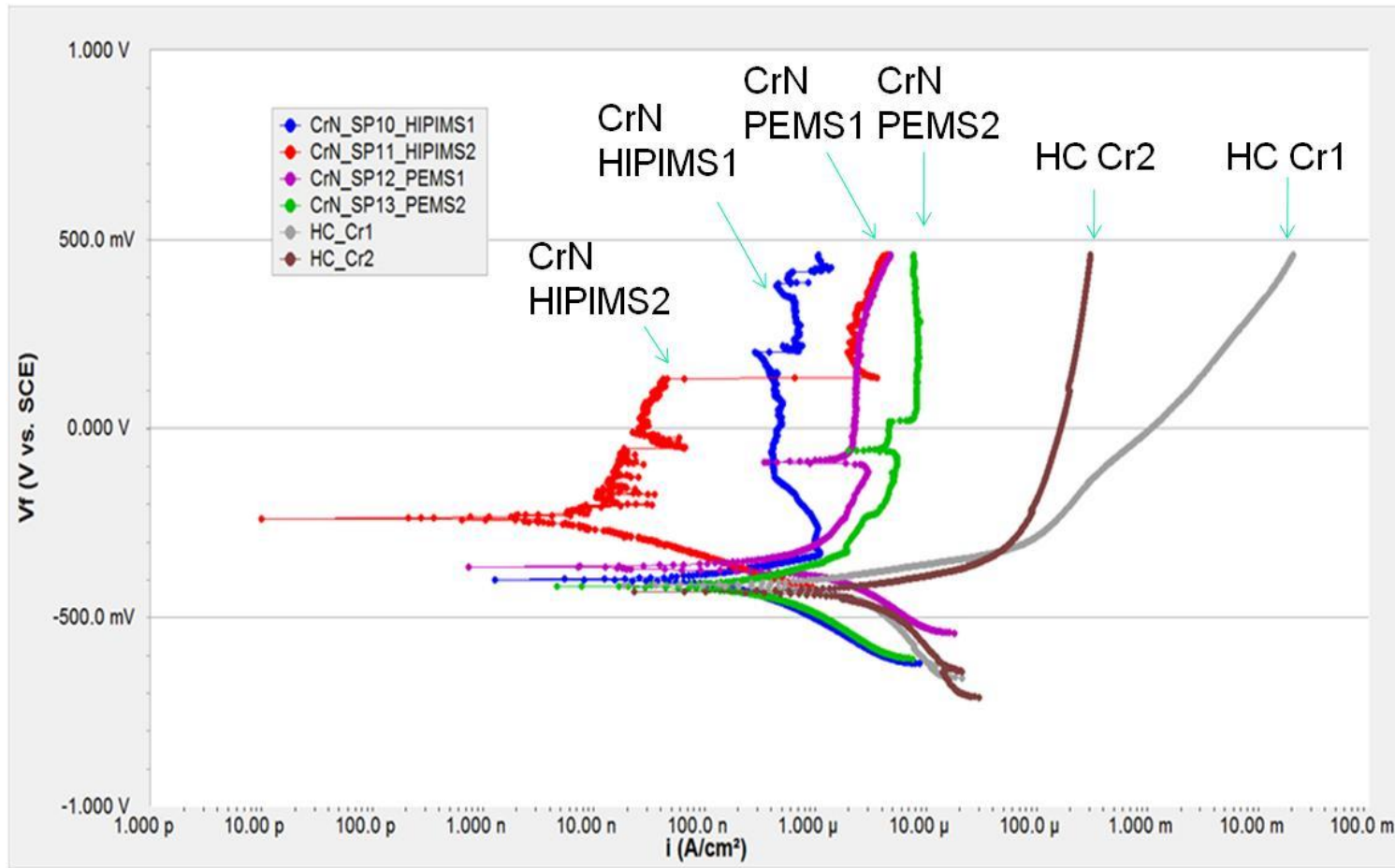
From- Jianliang Lin, William Sproul, John Moore, Sabrina Lee, S. Myers, Surf Coat Tech 205 (2010), 3226-3234.



- ASTM D1141-98 “Standard Practice for the Preparation of Substitute Ocean Water”
- ASTM G3-89 “Standard Practice for Conventions Applicable to Electrochemical Measurements in Corrosion Testing”
- ASTM G5-94 “Standard Reference Test Method for Making Potentiostatic and Potentiodynamic Anodic Polarization Measurements”

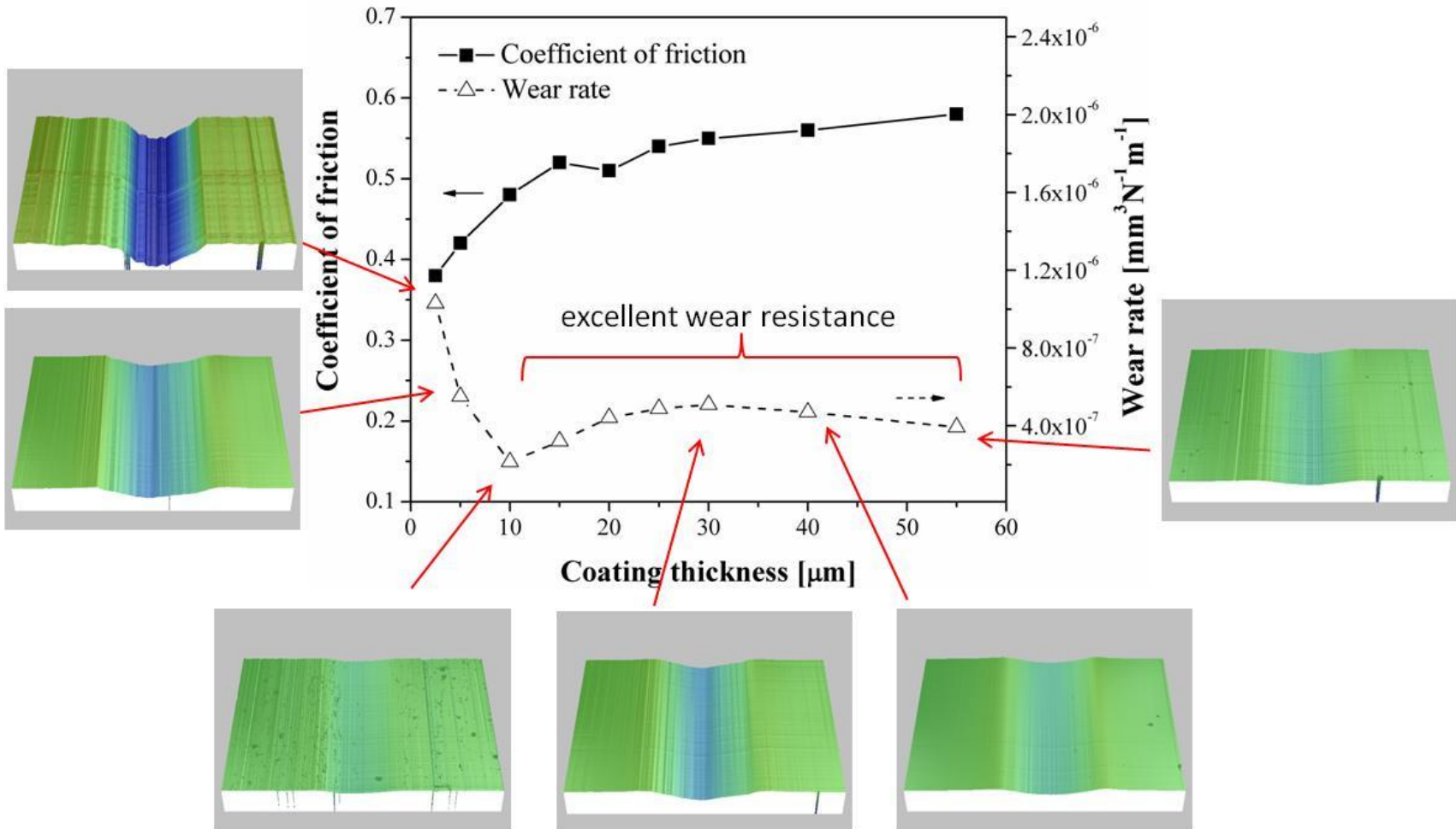


PEMS and HIPIMS CrN coatings showed 2 orders of magnitude improved corrosion resistance compared to electroplated HC Cr



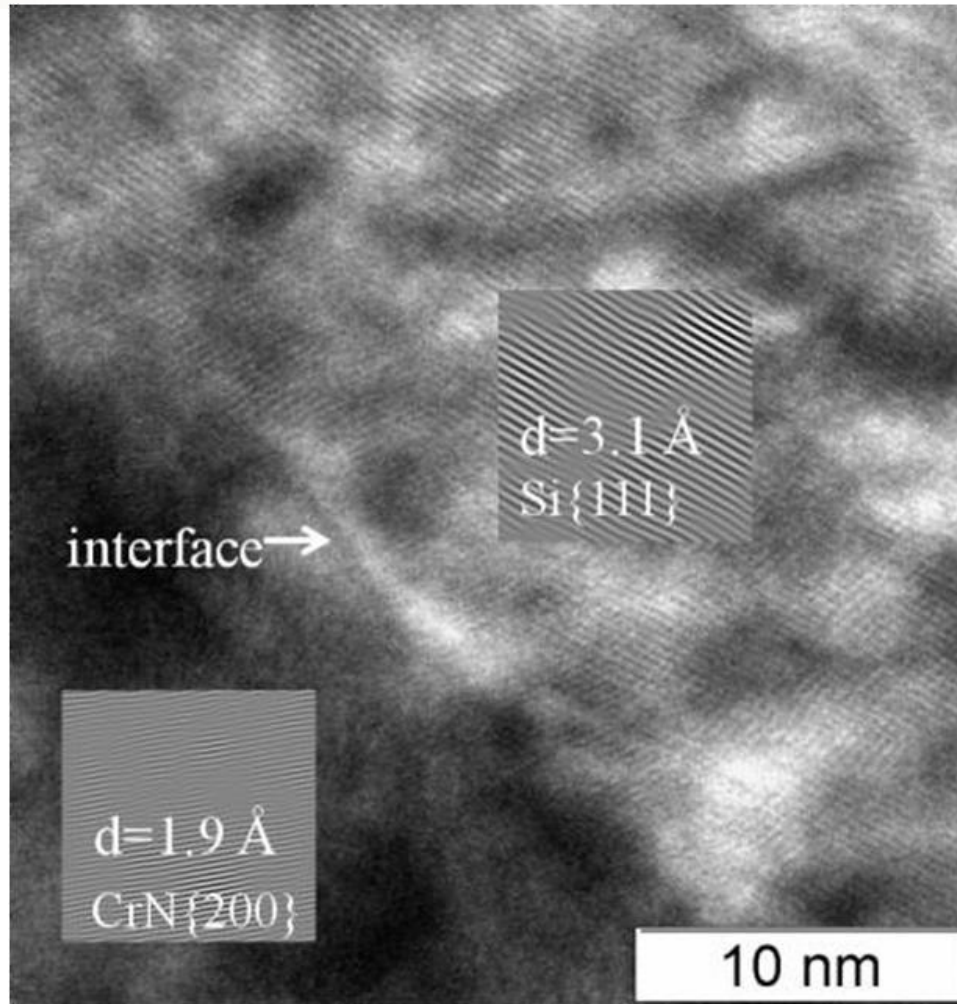
Current Density in $\mu\text{A}/\text{cm}^2$, Log Scale

Test conditions: 10 N normal load, 200 rpm, 5hr, sliding against a 5 mm Al₂O₃ ball

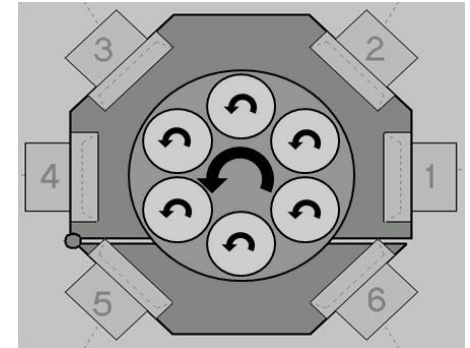
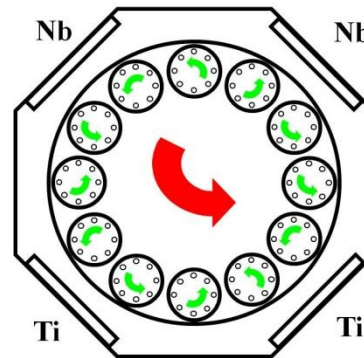
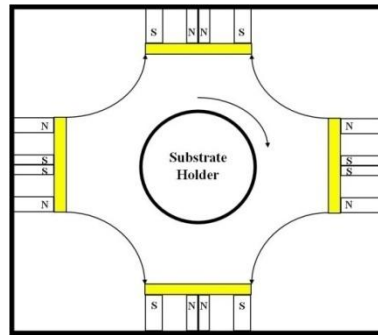
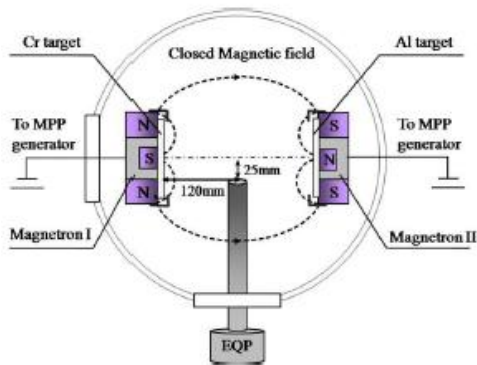
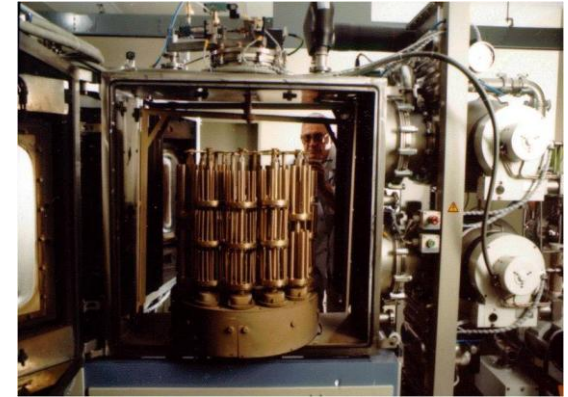
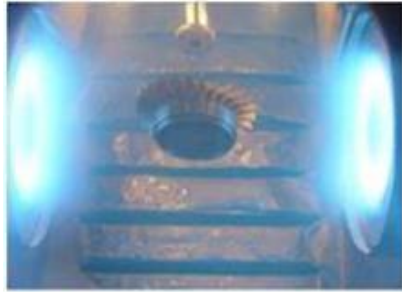
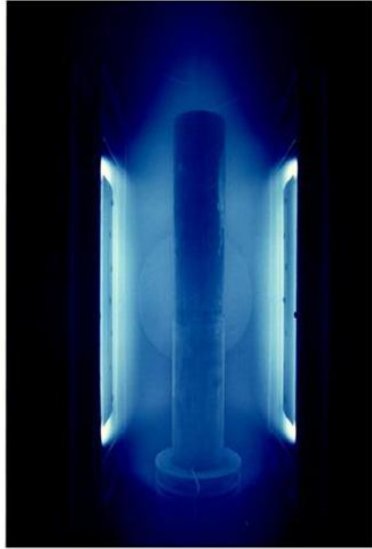


* Jianliang Lin, William Sproul, John Moore, Sabrina Lee, S. Myers, Surf Coat Tech 205 (2010), 3226-3234.

Clean and Dense Interface Microstructure of MPP CrN Film on Si



From- J. Lin, W.D. Sproul, J. Moore, S. L. Lee, R. Chistyakov, 'Recent advances in Modulated Pulsed Power Magnetron Sputtering for Surface Engineering', JOM, June (2011) 48-58.



- ❑ *New PVD technology PEM with higher plasma density, and HIPIMS-MPP processes generating high intensity metal plasma for deposition of dense quality coatings with less columnar microstructure.*
- ❑ *New technology successfully deposited Ta 100-150 μm on 120mm diameter cylinder bore; Ta phase is sensitive to deposition parameters.*
- ❑ *New technology successfully deposited 10-55 μm fcc CrN coatings on steel; formation of CrN and Cr_2N phases depends on N_2 concentration.*
- ❑ *New thick PVD Ta demonstrated dense bcc Ta coatings with excellent ductility, microstructure, and high temperature properties.*
- ❑ *New thick PVD CrN demonstrated dense coatings, good microstructure, high hardness, good modulus, superior corrosion resistance, superior wear resistance properties.*
- ❑ *New technology can deposit environmental-friendly coatings, Ta & CrN, for potential replacement of production HC Cr coatings for ordnance.*